

PATENT APPLICATION

Docket No.: 109589

N THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Fusao SHIMIZU

Application No.: 09/863,447

Filed: May 24, 2001

SHAPE MEASUREMENT DEVICE

4/RAmdtA 11/30/01 C. McKenney

Director of the U.S. Patent and Trademark Office Washington, D. C. 20231

Sir:

For:

PRELIMINARY AMENDMENT
or of the U.S. Patent and Trademark Office
ngton, D. C. 20231

In response to the Notice of Omitted Items mailed July 23, 2001, and the Decision dismissing the July 30, 2001 Petition, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 9, delete lines 20-23.

Page 9, line 24 - page 10, line 17, delete current paragraphs and insert therefor:

Fig. 9 shows an explanatory figure for explanation of the procedure for measurement of the degree of planarity of a surface 98 of a carrier 18 utilizing the carrier shape measurement device according to the first embodiment of the present invention.

Fig. 10 shows an explanatory figure for explanation of an example of the situation and the measurement position when semiconductor wafers 97 are loaded into the carrier 18.

Fig. 11 shows a flow chart showing the operation for measuring the degree of planarity of the surface 98 of the carrier 18 utilizing the carrier shape measurement device according to the first embodiment of the present invention.